Pt. 63, Subpt. MMM, Table 2

Reference to subpart A	Applies to subpart MMM	Explanation
§ 63.7(e)(2)	Yes	
§ 63.7(e)(3)	Yes	Except § 63.1365 specifies less than 3 runs for certain tests.
§ 63.7(e)(4)	Yes.	
§ 63.7(f)	Yes	
§ 63.7(g)(1)	Yes	Except § 63.1368(a) specifies that the results of the performance test be submitted with the Notification of Compliance Status report
§ 63.7(g)(2)	N/A	Reserved.
§ 63.7(g)(3)	Yes	Tieserveu.
§ 63.7(h)	Yes	
§ 63.8(a)(1)–(2)	Yes	
§ 63.8(a)(3)	N/A	Reserved.
§ 63.8(a)(4)	Yes	Tieserveu.
§ 63.8(b)(1)	Yes	
§ 63.8(b)(2)	No	§ 63.1366 specifies CMS requirements.
§ 63.8(b)(3)–(c)(3)	Yes	Except the submittal date of the immediate startup, shutdown, and malfunction reports for CMS events shall be 2 days as in §63.6(e)(3)(iv).
§ 63.8(c)(4)	No	§ 63.1366 specifies monitoring frequencies.
§ 63.8(c)(5)–(8)	No	3 - 4
§ 63.8(d)–(f)(3)	Yes	
§ 63.8(f)(4)	Yes	Except § 63.1368(b) specifies that requests may also be included in the Precompliance report.
§ 63.8(f)(5)	Yes	
§ 63.8(f)(6)	No	Subpart MMM does not require CEM's.
§ 63.8(g)	No	§ 63.1366 specifies data reduction procedures.
§ 63.9(a)–(d)	Yes	3 correde openines data readouer presedures.
§ 63.9(e)	No	
§ 63.9(f)	No	Subpart MMM does not contain opacity and visible emission standards.
§ 63.9(g)	No	Caspart minim accounts comain opacity and violate comecion claridates.
§ 63.9(h)(1)	Yes	
§ 63.9(h)(2)(i)	Yes	Except § 63.1368(a)(1) specifies additional information to include in the Notification of Compliance Status report.
§ 63.9(h)(2)(ii)	No	§ 63.1368 specifies the Notification of Compliance Status report is to be submitted within 150 days after the compliance date.
§ 63.9(h)(3)	Yes	,
§ 63.9(h)(4)	N/A	Reserved.
§ 63.9(h)(5)–(6)	Yes	
63.9(i)	Yes.	
63.9(j)	No	§ 63.1368(h) specifies procedures for notification of changes.
§ 63.10(a)–(b)(1)	Yes	(,,,,,,,
§ 63.10(b)(2)	No	§ 63.1367 specifies recordkeeping requirements.
§ 63.10(b)(3)	Yes	,
§ 63.10(c)	Yes	
§ 63.10(d)(1)	Yes	
§ 63.10(d)(2)	Yes	
§ 63.10(d)(3)	No	Subpart MMM does not include opacity and visible emission standards.
§ 63.10(d)(4)	Yes	The state of the s
§ 63.10(d)(5)	Yes	Except that actions and reporting for batch processes do not apply during start- up and shutdown.
§ 63.10(e)(1)-(2)(i)	Yes	The second secon
§ 63.10(e)(2)(ii)	No	Subpart MMM does not include opacity monitoring requirements.
§ 63.10(e)(3)	Yes	
§ 63.10(e)(4)	No	Subpart MMM does not include opacity monitoring requirements.
§ 63.10(f)	Yes	The state of the s
§ 63.11–§ 63.15	Yes.	

 $[64\;\mathrm{FR}\;33589,\,\mathrm{June}\;23,\,1999,\,\mathrm{as}\;\mathrm{amended}\;\mathrm{at}\;67\;\mathrm{FR}\;59355,\,\mathrm{Sept.}\;20,\,2002]$

Table 2 to Subpart MMM of Part 63—Standards for New and Existing PAI Sources

Emission source	Applicability	Requirement	
Process vents	Existing: Processes having uncontrolled organic HAP emissions ≥0.15 Mg/yr. Processes having uncontrolled HCl and chlo- rine emissions ≥6.8 Mg/yr. Individual process vents meeting flow and mass emissions criteria that have gaseous organic HAP emissions controlled to less than 90% on or after November 10, 1997.	90% for organic HAP per process or to outlet concentration of ≤20 ppmv TOC. 94% for HCl and chlorine per process or to outlet HCl and chlorine concentration of ≤20 ppmv. 98% gaseous organic HAP control per vent or ≤20 ppmv TOC outlet limit.	

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Environmental Protection Agency

Emission source	Applicability	Requirement	
	New:		
	Processes having uncontrolled organic HAP emissions ≥0.15 Mg/yr.	98% for organic HAP per process or ≤20 ppmv TOC.	
	Processes having uncontrolled HCl and chlorine emissions ≥6.8 Mg/yr and <191 Mg/yr.	94% for HCl and chlorine per process or to outlet concentration of ≤20 ppmv HCl and chlorine.	
	Processes having uncontrolled HCl and chlorine emissions ≥191 Mg/yr.	99% for HCl and chlorine per process or to outlet concentration of ≤20 ppmv HCl and chlorine.	
Storage vessels	Existing: ≥75 m³ capacity and vapor pressure ≥3.45 kPa.	Install a floating roof, reduce HAP by 95% per vessel, or to outlet concentration of ≤20 ppmv TOC.	
	New: ≥38 m³ capacity and vapor pressure ≥16.5 kPa.	Same as for existing sources.	
	≥75 m³ capacity and vapor pressure ≥3.45 kPa	Same as for existing sources.	
Wastewater ^a	Existing: Process wastewater with ≥10,000 ppmw Table 9 compounds at any flowrate or ≥1,000 ppmw Table 9 compounds at ≥10 L/ min, and maintenance wastewater with HAP load ≥5.3 Mg per discharge event.	Reduce concentration of total Table 9 compounds to <50 ppmw (or other options).	
	New:		
	Same criteria as for existing sources	Reduce concentration of total Table 9 compounds to <50 ppmw (or other options).	
	Total HAP load in wastewater POD streams ≥2,100 Mg/yr	99% reduction of Table 9 compounds from all streams.	
Equipment leaks	Subpart H	Subpart H with minor changes, including monitoring frequencies consistent with the proposed CAR.	
Product dryers and bag dumps.	Dryers used to dry PAI that is also a HAP, and bag dumps used to introduce feedstock that is a solid and a HAP.	Particulate matter concentration not to exceed 0.01 gr/dscf.	
Heat exchange systems	Each heat exchange system used to cool proc- ess equipment in PAI manufacturing oper- ations.	Monitoring and leak repair program as in HON.	

 $^{^{\}rm a}\text{Table 9}$ is listed in the appendix to subpart G of 40 CFR part 63.

Table 3 to Subpart MMM of Part 63—Monitoring Requirements for Control Devices $^{\rm A}$

Control device	Monitoring equipment required	Parameters to be monitored	Frequency
All control devices	Flow indicator installed at all bypass lines to the at- mosphere and equipped with continuous recorder or.	Presence of flow diverted from the control device to the atmosphere or.	Hourly records of whether the flow indicator was operating and whether a diversion was detected at any time during each hour.
	Valves sealed closed with car-seal or lock-and-key configuration.	Monthly inspections of sealed valves.	Monthly.
Scrubber	Liquid flow rate or pressure drop mounting device. Also a pH monitor if the scrubber is used to control acid emissions	Liquid flow rate into or out of the scrubber or the pres- sure drop across the scrub- ber	1. Every 15 minutes.
		pH of effluent scrubber liq- uid.	2. Once a day.
Thermal incinerator	Temperature monitoring de- vice installed in firebox or in ductwork immediately downstream of firebox b.	Firebox temperature	Every 15 minutes.
Catalytic incinerator	Temperature monitoring de- vice installed in gas stream immediately before and after catalyst bed.	Temperature difference across catalyst bed.	Every 15 minutes.
Flare	Heat sensing device installed at the pilot light.	Presence of a flame at the pilot light.	Every 15 minutes.
Boiler or process heater <44 megawatts and vent stream is not mixed with the primary fuel.	Temperature monitoring device installed in firebox ^b .	Combustion temperature	Every 15 minutes.